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2818

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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AUG 29 2002
TECHNOLOGY CENTER 2818

In re application of:

TUE NGUYEN et al.

Application No.: 09/898,439

Filed: July 5, 2001

For: Plasma semiconductor processing system
and method

Examiner: Le, Dung A.

Art Unit: 2818

ELECTION/RESTRICTIONS

Elect
G. Stanley
8-5-02

Assistant Commissioner for Patents

Washington, D.C. 20231

Sir:

In response to the Office Action dated July 18, 2002, please amend the
above-referenced application as follows.

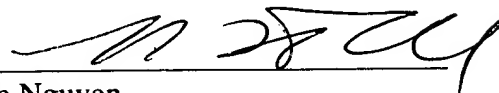
ELECTION/RESTRICTIONS

Please select group I, claims 1-16 and 20, drawn to an apparatus of
making a semiconductor device, classified in class 29/025.010.

This election is without traverse.

If for any reason the Examiner believes that a telephone conference would in any way expedite prosecution of the subject application, the Examiner is invited to telephone the undersigned at 510-438-4881.

Respectfully submitted,




Tue Nguyen

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to:

Assistant Commissioner for Patents
Washington, D.C. 20231

On August 12, 2002

By: 

Tue Nguyen